HOW DO YOU MAKE CONTINUOUS IMPROVEMENT PROFITABLE?

Time-of-Flight Secondary Ion Mass Spectrometry (TOF-SIMS -*Static SIMS*)

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成分分析仪器|表面测试仪器|样品前处理仪器

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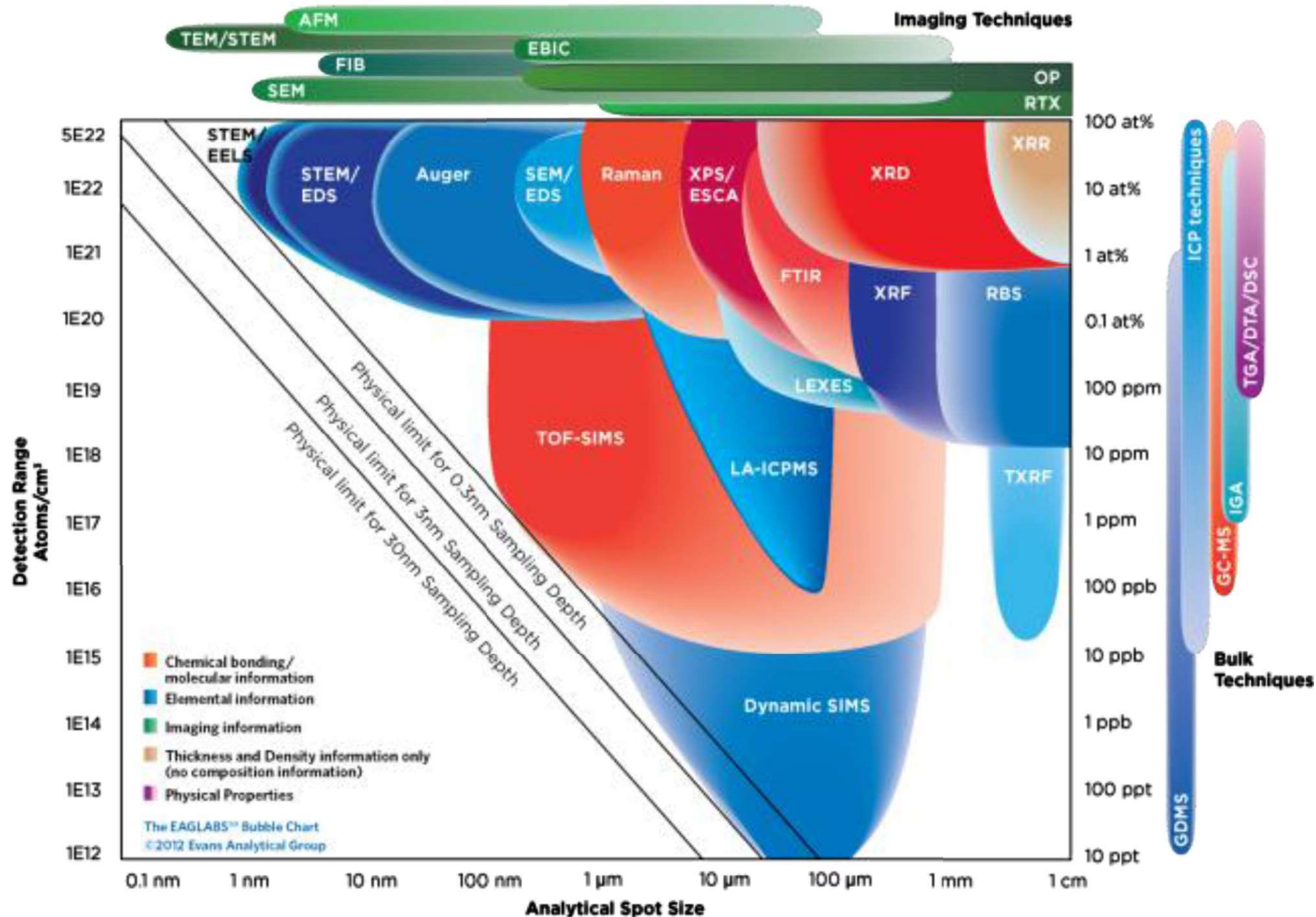
TOF-SIMS



TOF-SIMS is a very surface sensitive technique providing full elemental and molecular analysis with very good detection limits.

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Key Applications

- Surface characterization of organic and elemental materials
- Mapping distributions of surface species
- Contaminant identification (< ppm)
  - Elemental
  - Molecular
- Failure analysis
  - Adhesion
  - Bond Pads
  - Coatings
- Evaluation of cleaning processes (QA/QC)
- Identification of stains, discolorations, and hazes
- Molecular depth profiling of organic materials

SEMI-CRYSTALLINE RESIN? HOW DO YOU MINIMIZE PROCESS IMPURITIES? HOW DO YOU SPEED UP INNOVATION? HOW DO YOU PREVENT FAILURE? HOW DO YOU
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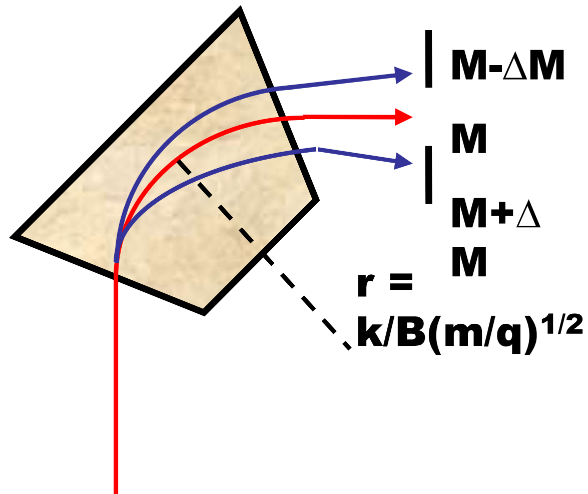
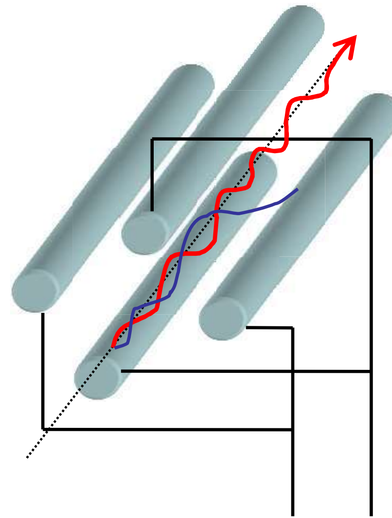
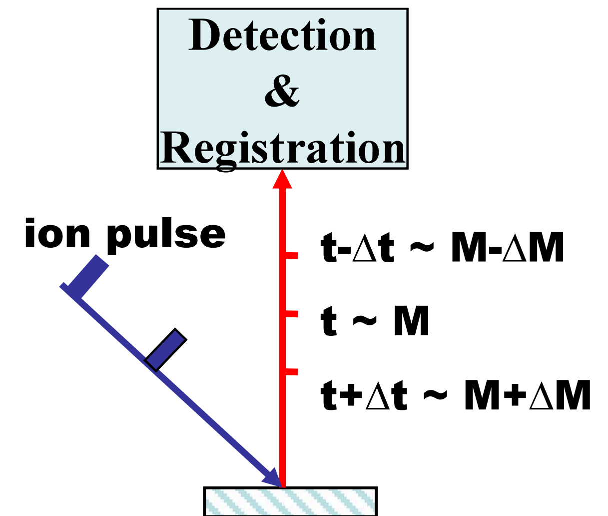
SIMS Instrument Type

Magnetic sector	Quadrupole	Time of Flight
		
	Vo(t) = Vc+Vs cosωt	
m/q ~ B	**m/q ~ V(f)**	**m/q ~ t**
Cameca	PHI, Atomika	PHI, IonTof

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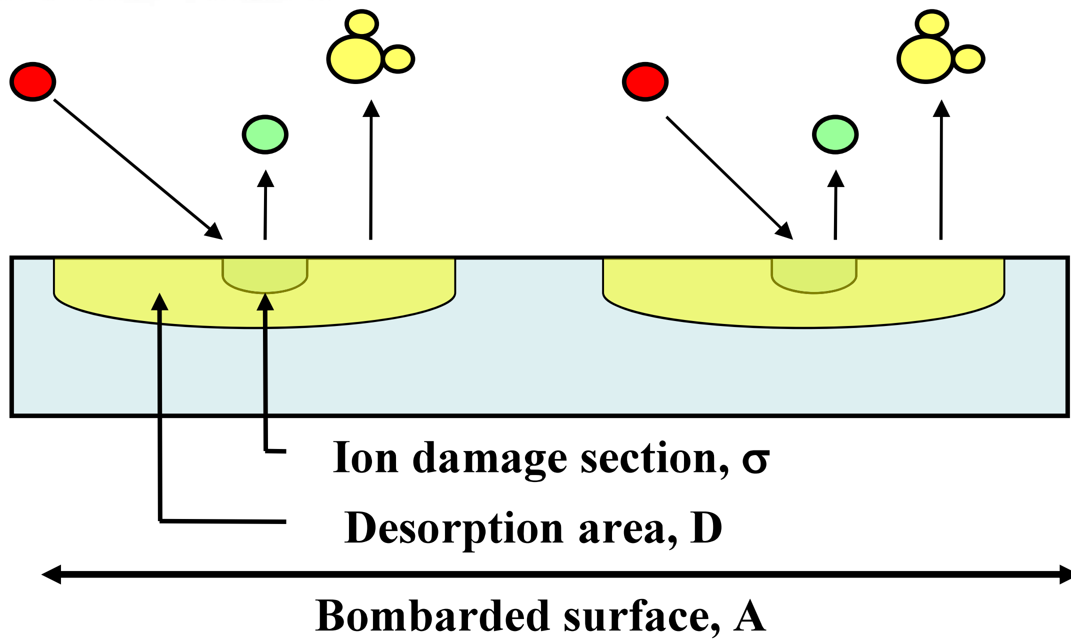
Dynamic vs. Static SIMS



	Σσ << A Static SIMS	Σσ = A Dynamic SIMS
Primary ion dose	<1E12 ions/cm2	>1E12 ions/cm2
Information	Chemical	Elemental
Analysis	Only surface	Depth profile
Instrument	TOF	Magnetic & Quad

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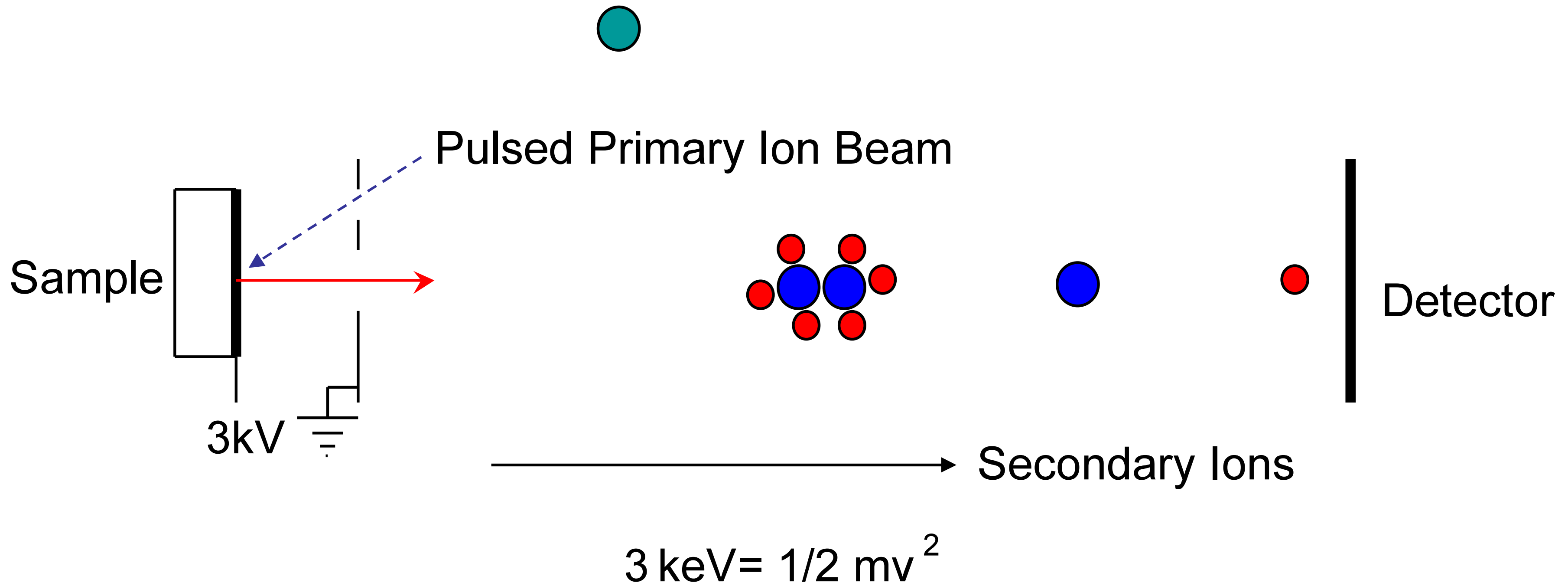
Time-of-Flight SIMS: Basic Principles



Measure spectrum in flight time: $t = k(m)^{1/2}$

Convert time axis to mass: $m = at^2 + b$

Light Ions arrive at the detector first, with sequentially heavier Ions following later in time. Each pulse of primary ions produces a full mass spectrum of secondary ions

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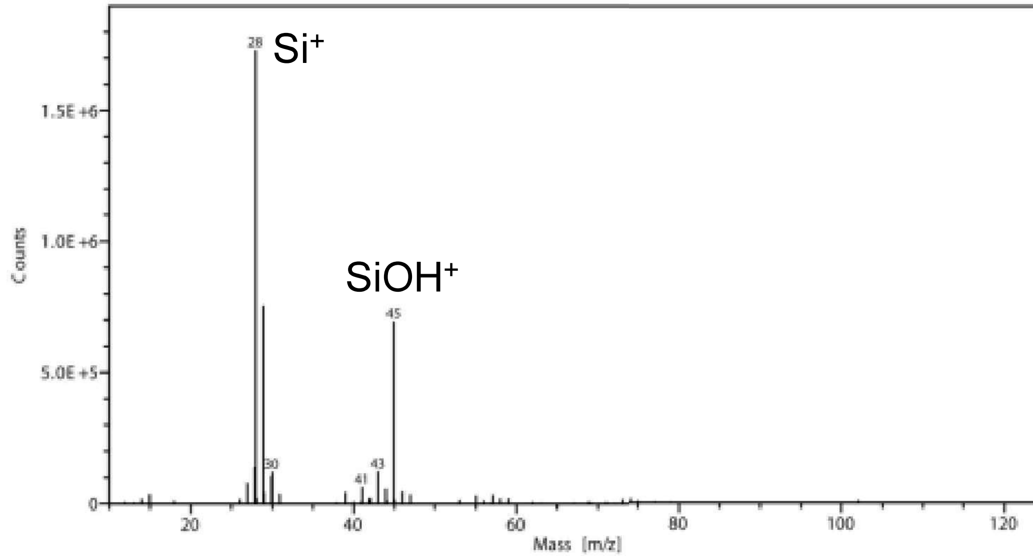
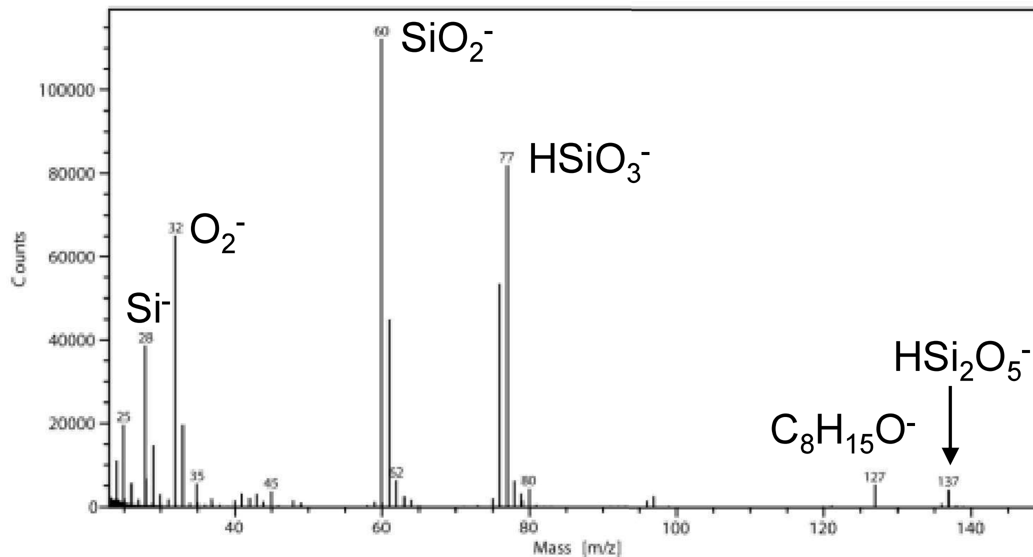
Typical Data (Silicon Wafer)



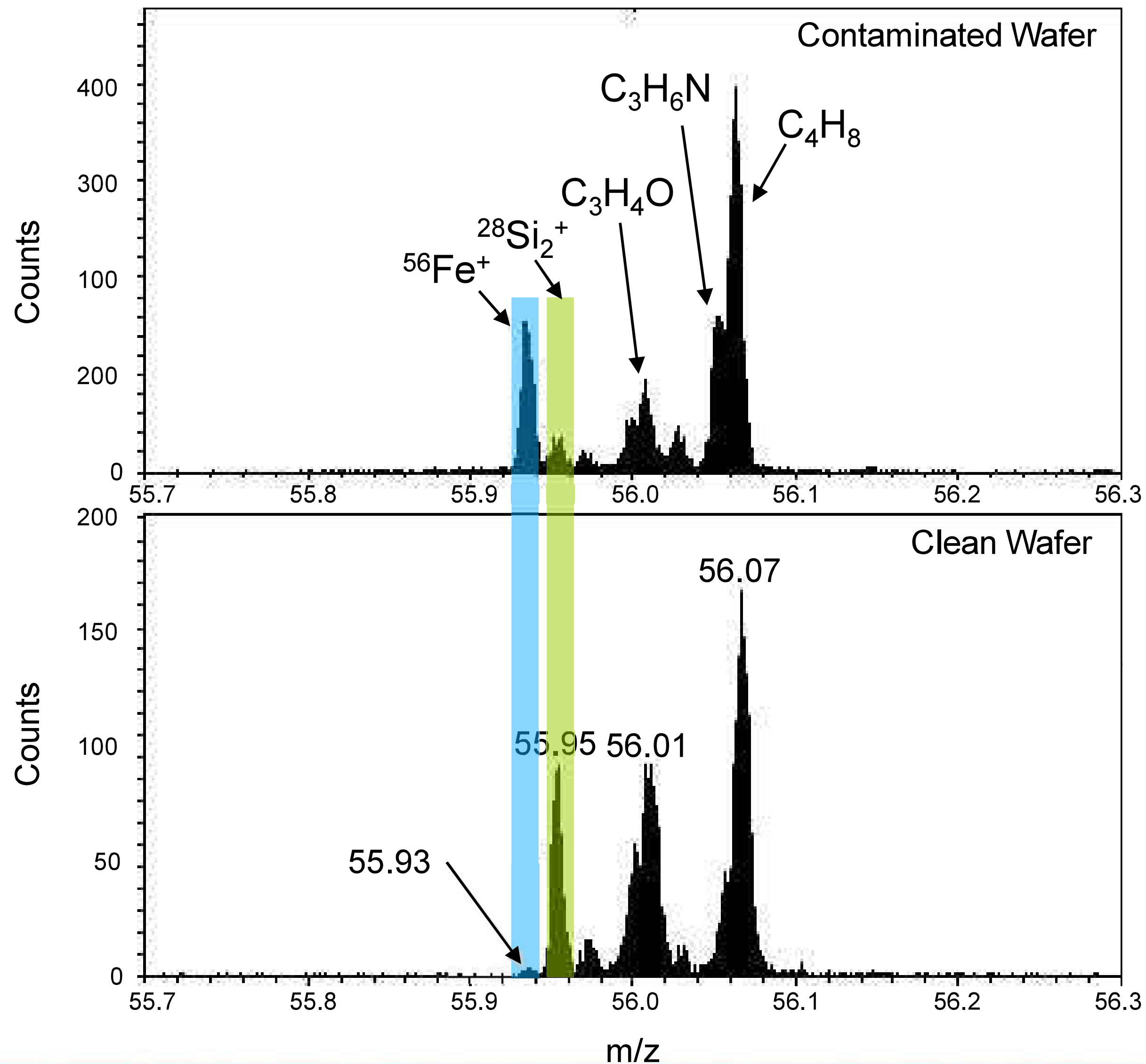
Positive ion spectrum



Negative ion spectrum

Typical Data

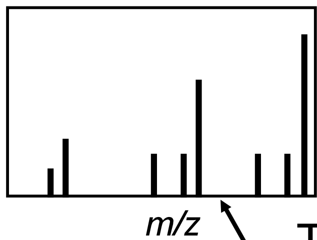
Silicon Wafer - High Mass Resolution



Typical Data

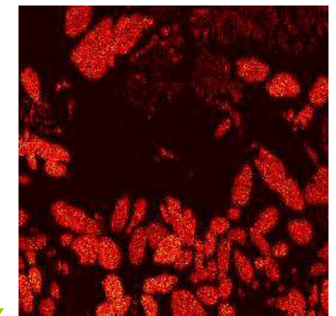
TOF-SIMS Imaging of Alumina-Zirconia-Silica Materials

Region 1 Spectrum

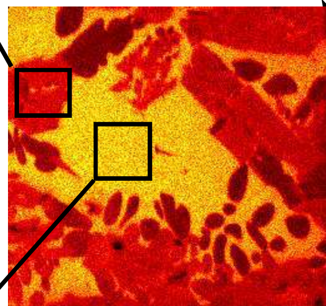


Primary Ion Beam

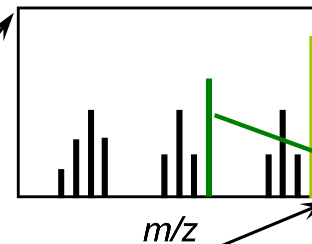
Chemical Map 1



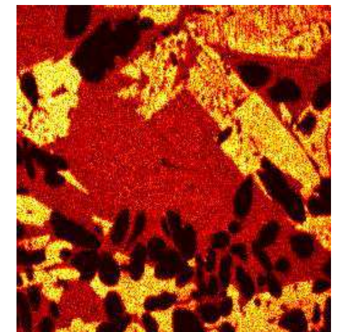
Total Ion Image



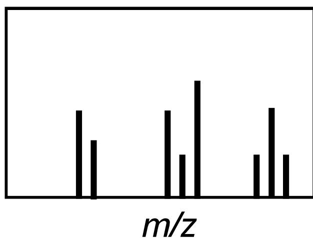
Total Area Spectrum

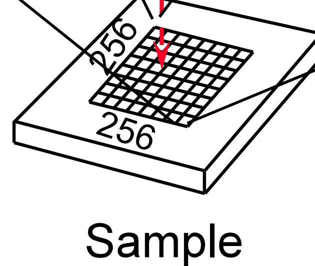


Chemical Map 2



Region 2 Spectrum





Sample

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Example Applications

- Residue on flat panel display
- Organic contamination on Si surfaces

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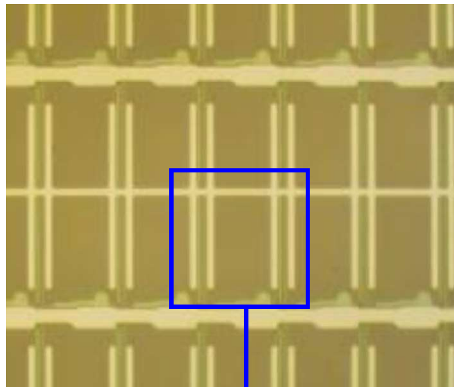
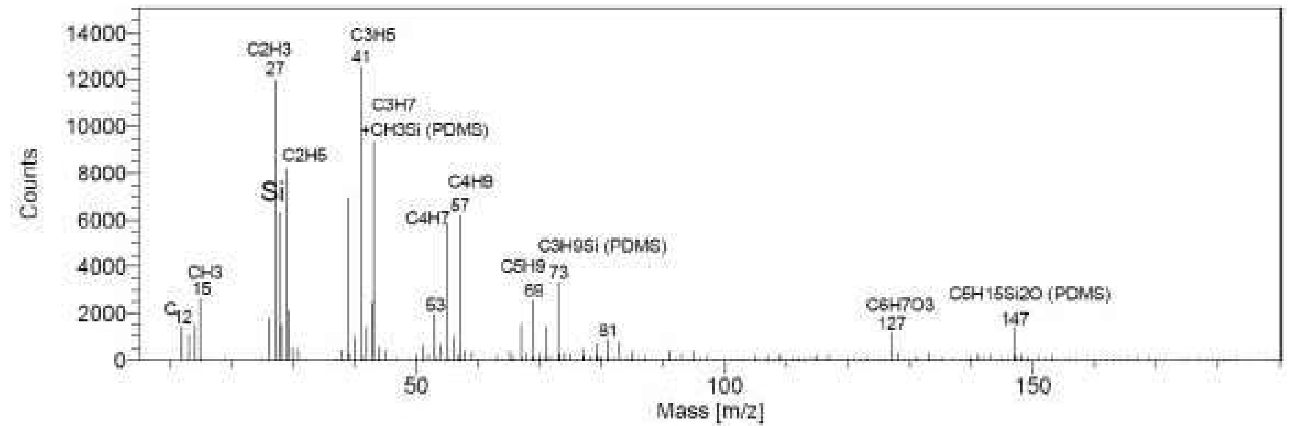
Residue on Flat Panel TFT

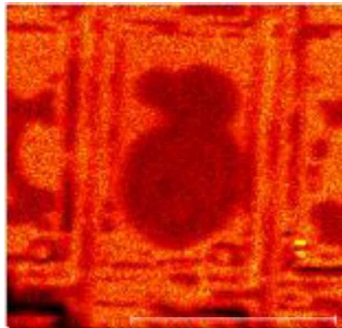
Photo of surface



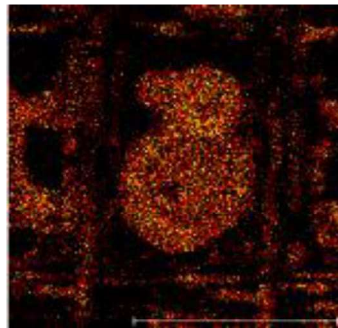
Mass spectrum



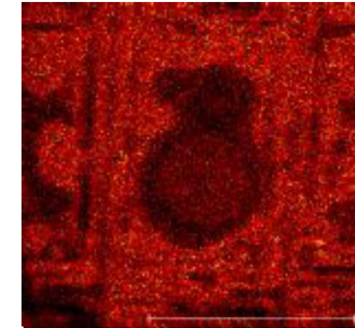
Total ion image



C_3H_9Si image (silicone)



C_2H_3 image (general hydrocarbon)



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Organic Contamination on Surfaces

- Airborne Molecular Contamination (AMC) can deposit on product and processing equipment and cause yield loss, hazing of optics, etc.
- AMC can be produced by
  - cleanroom construction materials
  - process chemicals
  - outside environment
  - HVAC system
  - gloves, garments, wipers, people, etc.
- Reference spectra are available to identify a wide range of common organic materials that can contaminate surfaces

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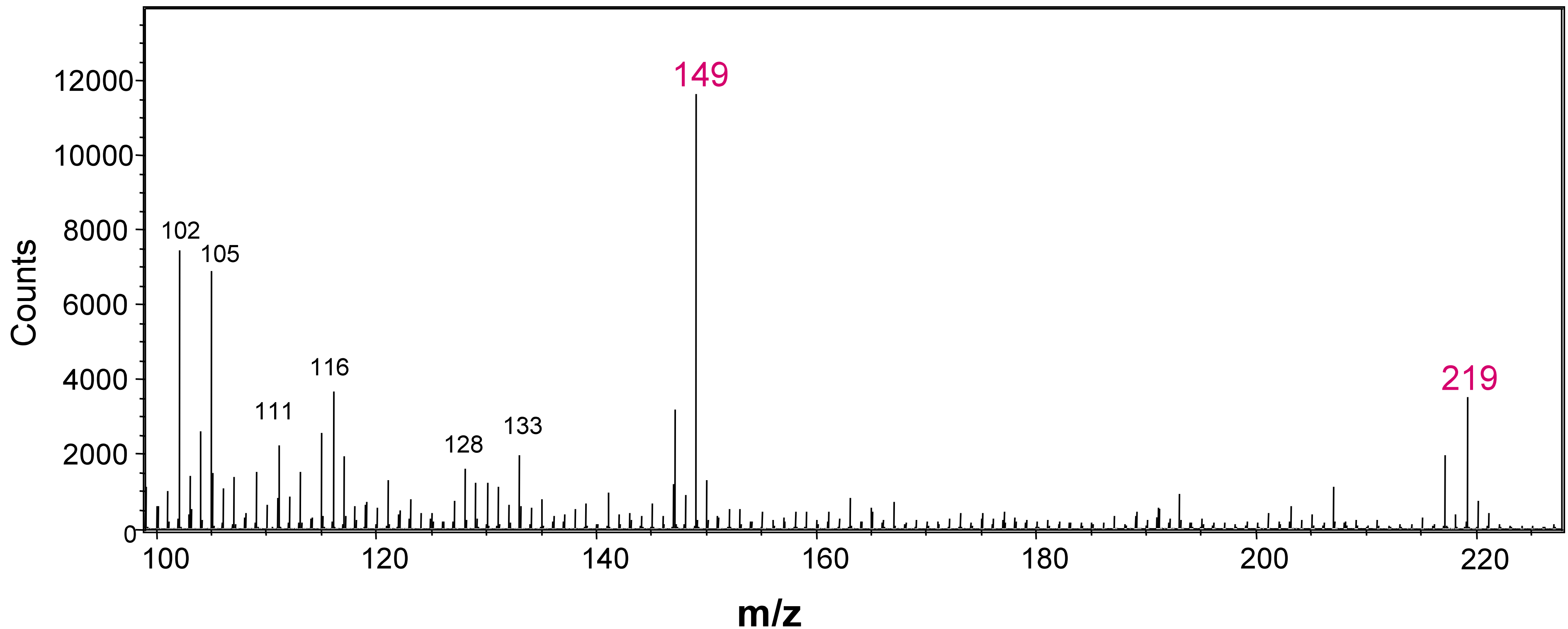
Organic Contamination on Si Wafer

Positive ion spectrum



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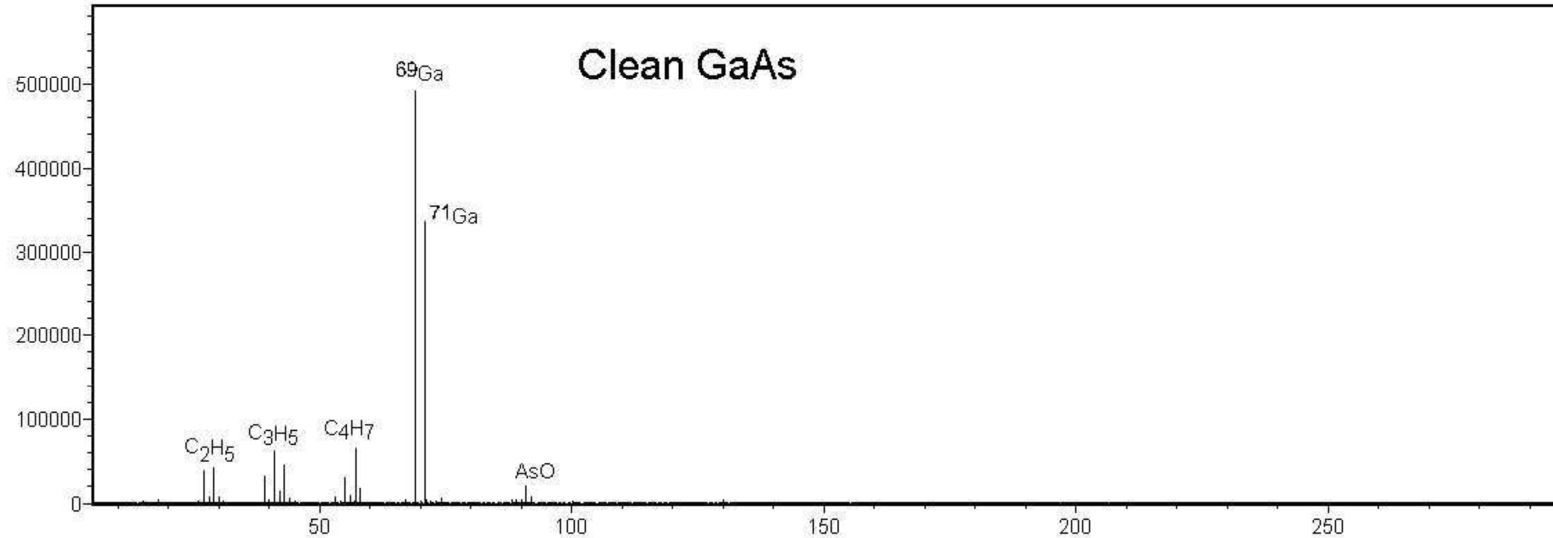
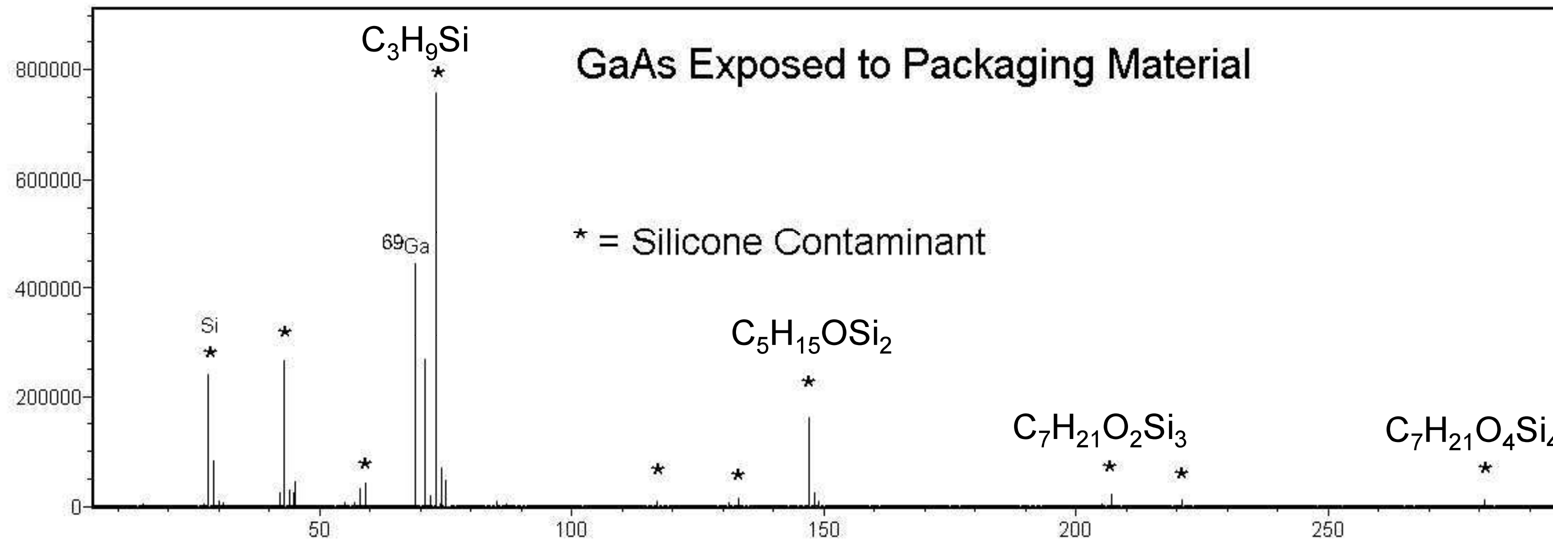
Contamination on GaAs Wafer from Packing Material





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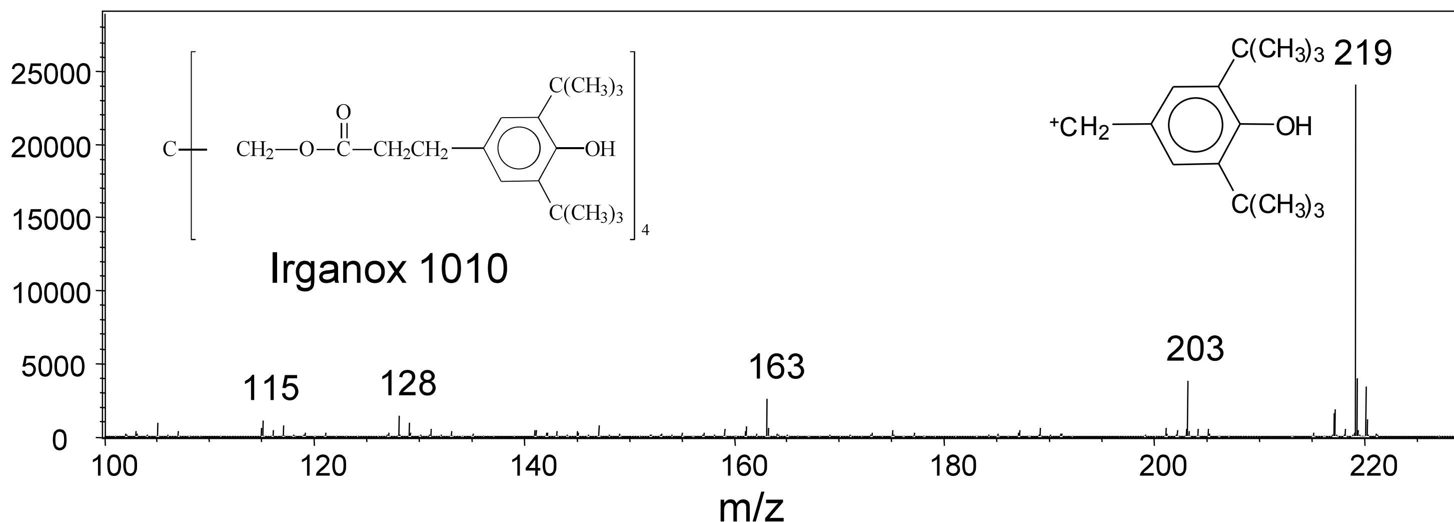
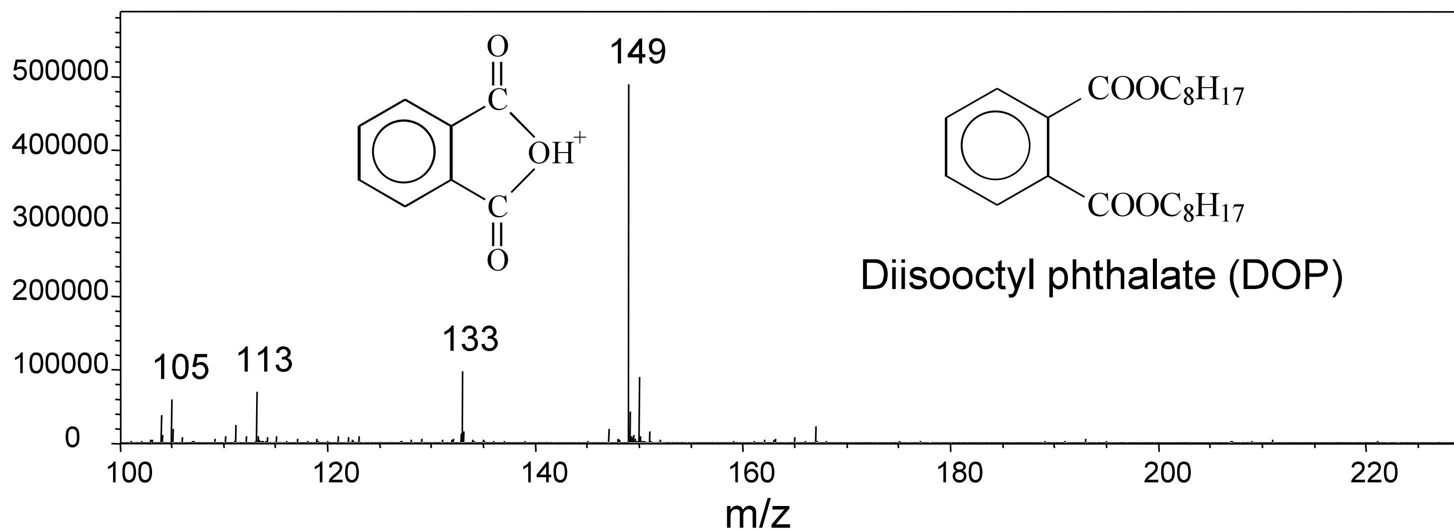
Reference Spectra from Compound Data Base





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Common Organic Surface Contaminants Detected by TOF-SIMS

Species	Possible Sources
Siloxane, (Polydimethylsiloxane, PDMS)	Machine lubricant, release agent, tape
Polyethylene oxide or polyethylene glycol	Surfactants, plasticizer, printing inks
Fatty acids	Finger oils, lubricants, polymer additives
Glycerides	Soap, polymer additives, releasing agents
Phosphates, sulfates, etc.	Cleaning reagent, surfactants, additives
Phthalate, etc.	Polymer additives, plastic parts, containers

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TOF SIMS profiling

By using an external sputtering gun, Intensity vs. Depth information can be obtained by two beam Sputtering/ Analysis process, just as Auger or XPS depth profiles

New generations of commercial TOF instrument often have options to add O2, Cs and Ar_n cluster sputtering beam

Gas Cluster Ion Beams (GCIB)

For ~40 years surface analysis of organics has been limited to the top surface or a surface accessible by cross sectioning. Traditional (monotonic) ion sputtering used on inorganics rapidly converts organics to amorphous carbon-like materials.

In the last 10 years it has been demonstrated that larger projectiles (SF_5, C_{60}, Ar clusters) sputter organics, but leave behind a pristine organic.

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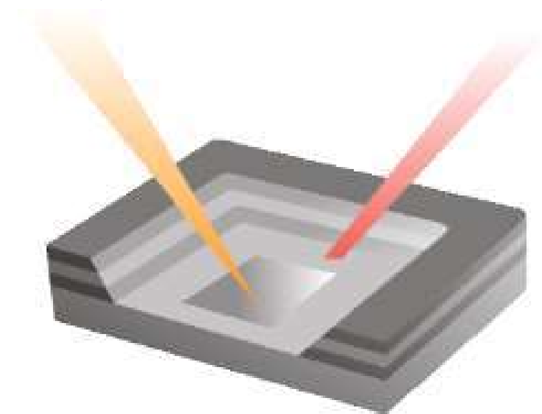
TOF Profiling Data Collection

Dual Beam Mode

Bi_3 : Analysis Beam Ar_n /Cs/O2 Sputter Beam



Ar+: 1-2 eV for organic materials

Profile formed by continuous sputtering by Ar_n interlaced with Bi_3 pulsed sputtering

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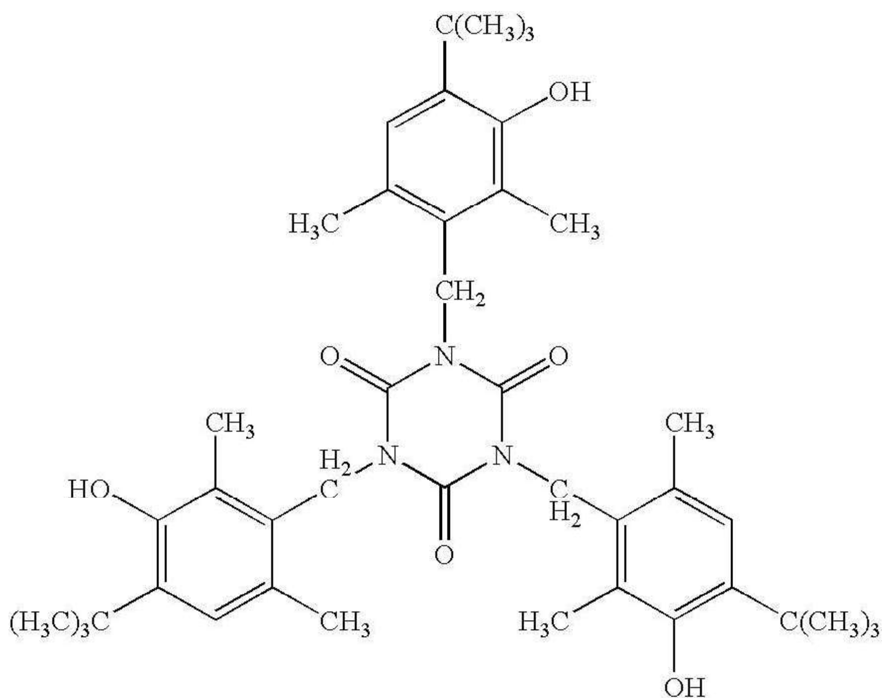
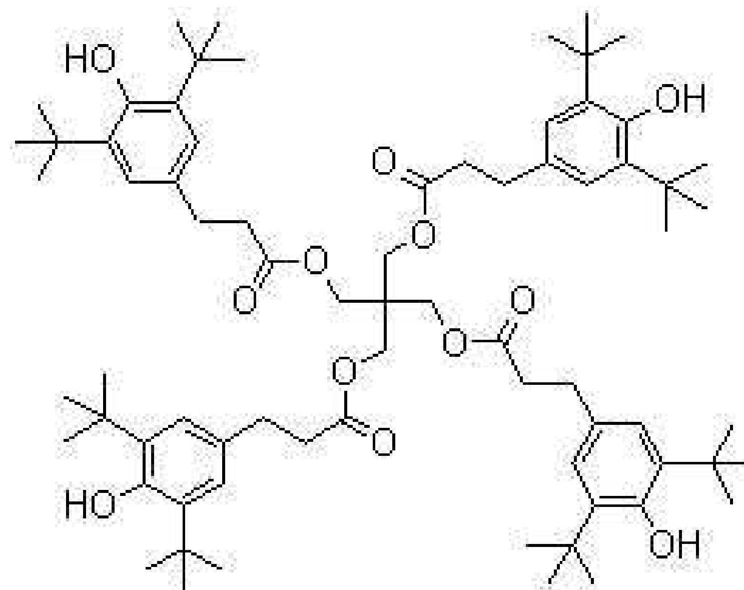
Molecular Depth Profiling

Reference film with organic delta layers

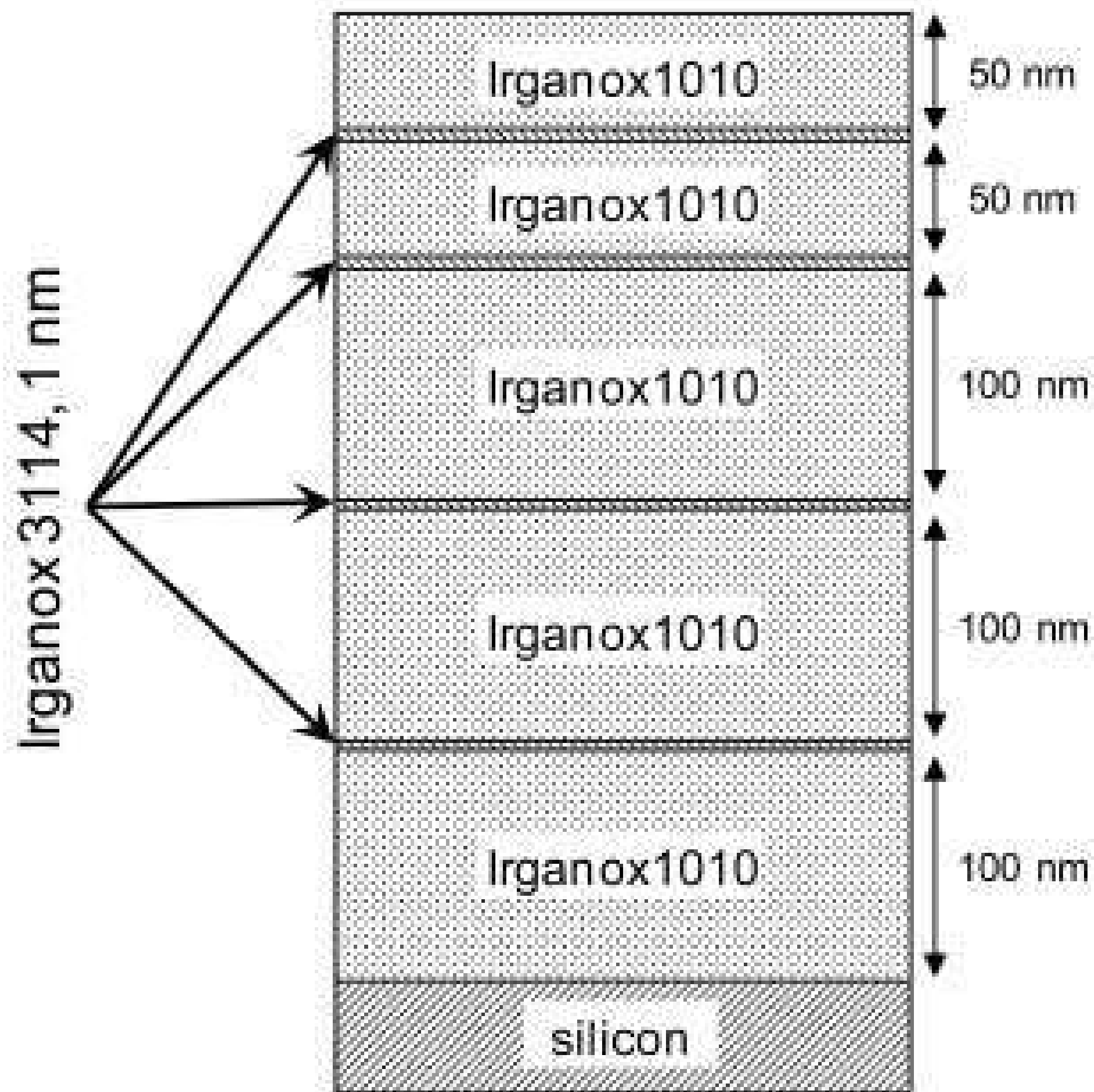
Irganox 3114, $C_{48}H_{69}N_3O_{12}$



Irganox 1010, $C_{73}H_{108}O_{12}$



Molecular Depth Profiling



A. Shard et al, *Anal Chem* ***84*** *7865-7873 (2012)*

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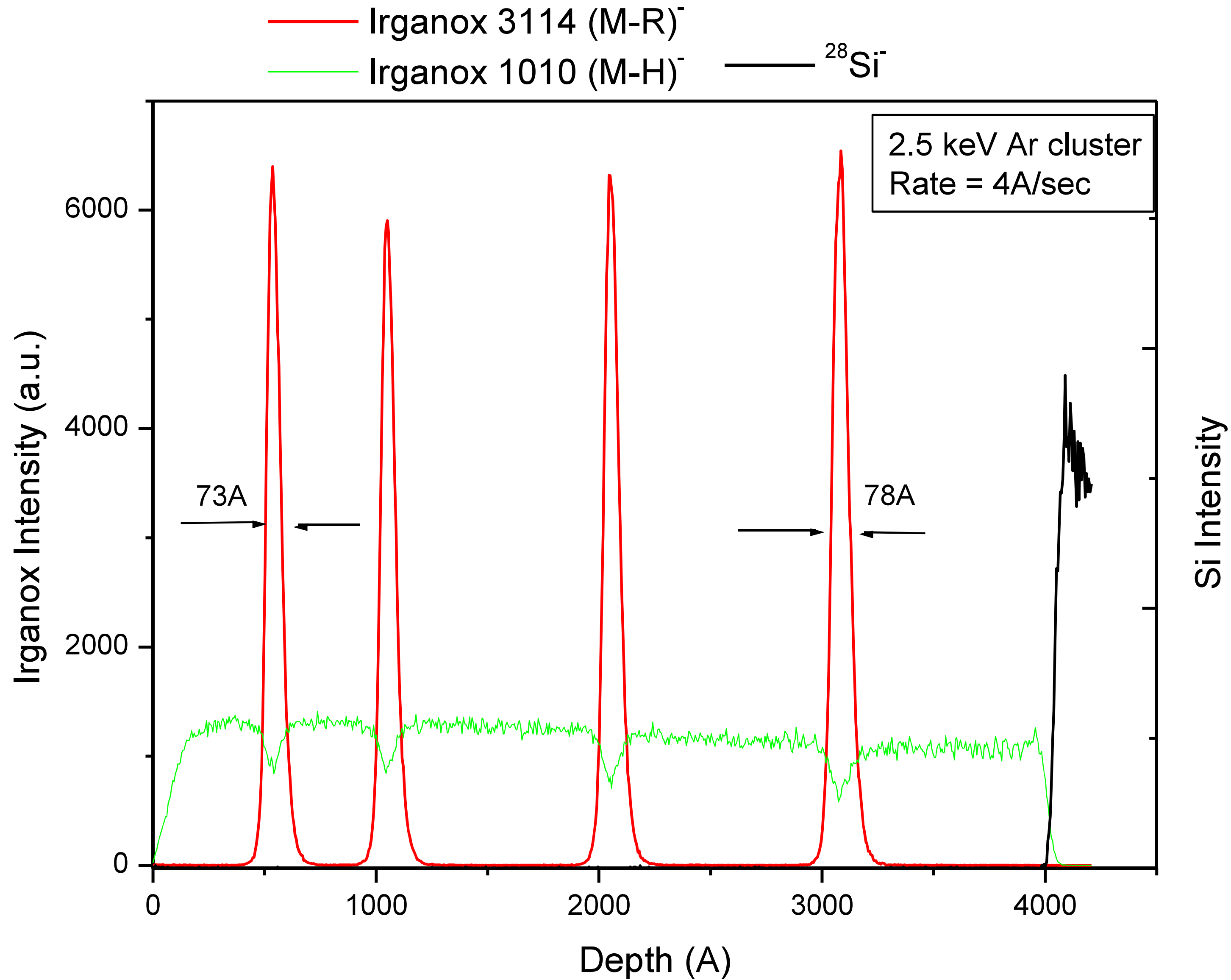
Molecular Depth Profiling



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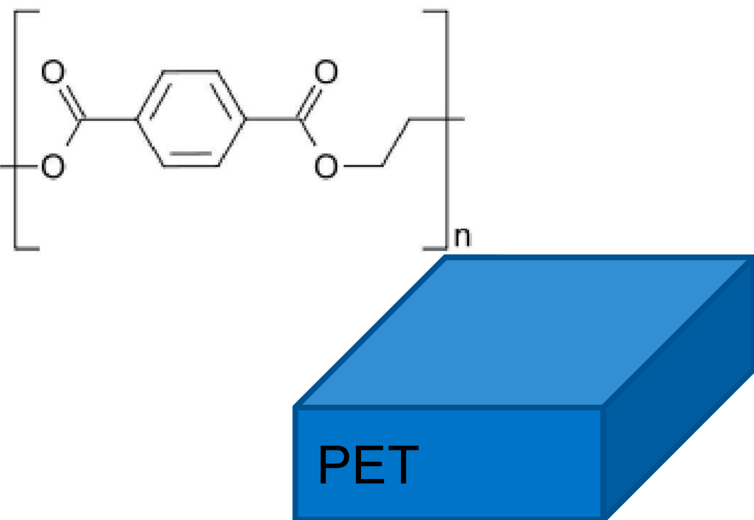
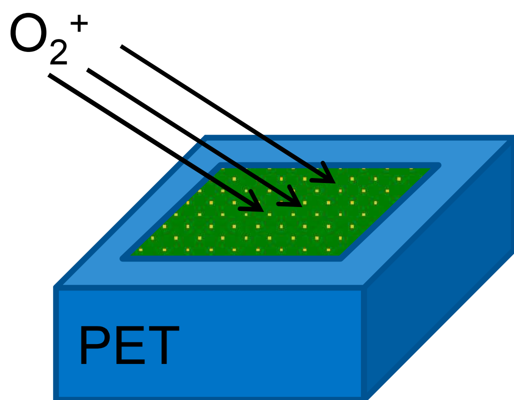
Molecular Depth Profiling-Damage Removal

Polyethylene terephthalate





File: surface p1_0.ita   Date: Fri Apr 10 08:17:20 2015   Polarity: Positive

Sample info: Primary Beam:
Sample   Species: Bi
Comment: Area: 150 x 150 µm²
Origin: Dose:

x10^6

surface p1_0

$C_xH_yO_z^+$

$C_xH_y^+$

$C_7H_4O^+$, $C_7H_5O^+$, $C_6H_4^+$, $C_6H_5^+$, $C_5H_5^+$, $C_4H_3^+$, $C_3H_3^+$, $C_3H_5^+$

x10^4

surface after O2 30sec sputter p2_0

C^+

After O_2 damage
(similar effect with Ar^+)

Intensity (counts)

Mass (u)

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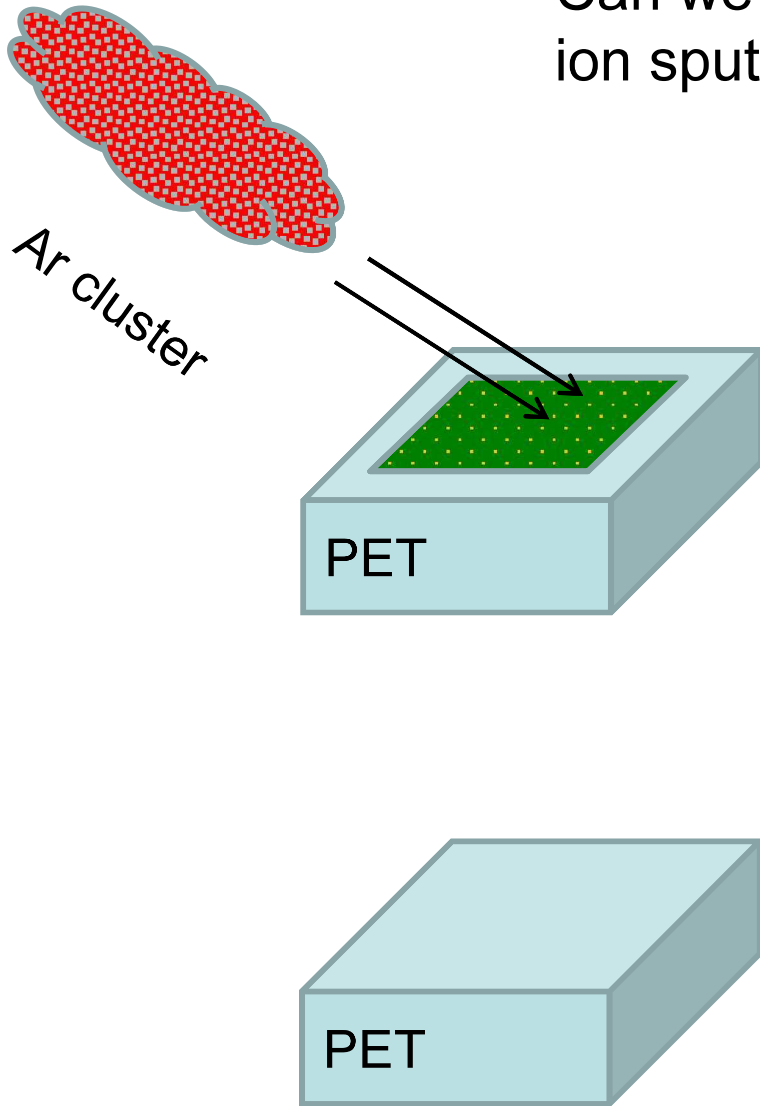
Molecular Depth Profiling-Damage Removal

- Can we recover a surface previously damaged by monato
  ion sputtering damage using Ar cluster bombardment?



x10^4
C+
2.5
2.0
1.5
1.0
0.5
x10^7
1.0
0.8
0.6
0.4
0.2
Intensity (counts)
10 20 30 40 50 60 70 80 90 100 110
Mass (u)
$C_xH_y^+$
$C_xH_yO_z^+$

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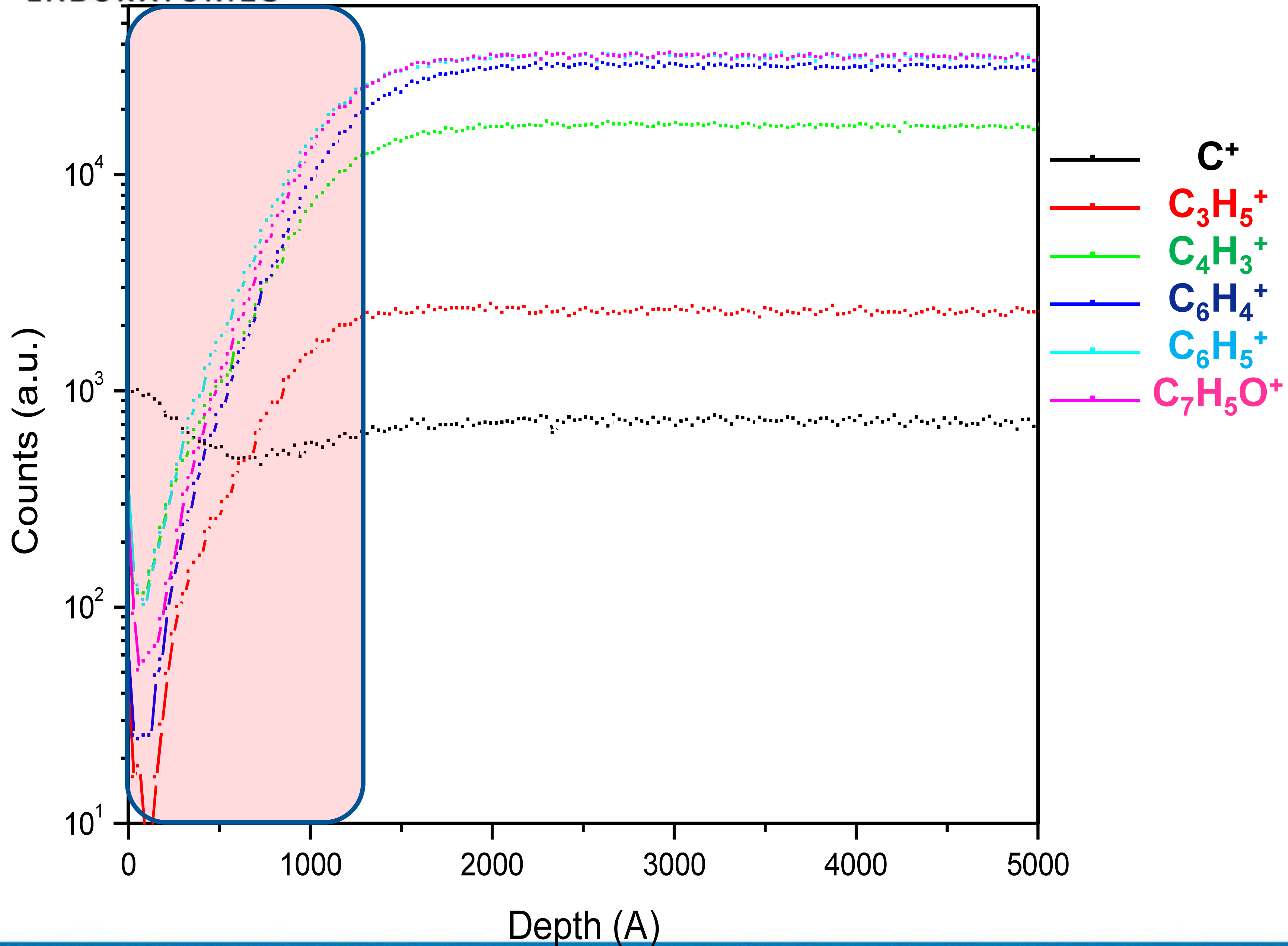
Molecular Depth Profiling-Damage Removal



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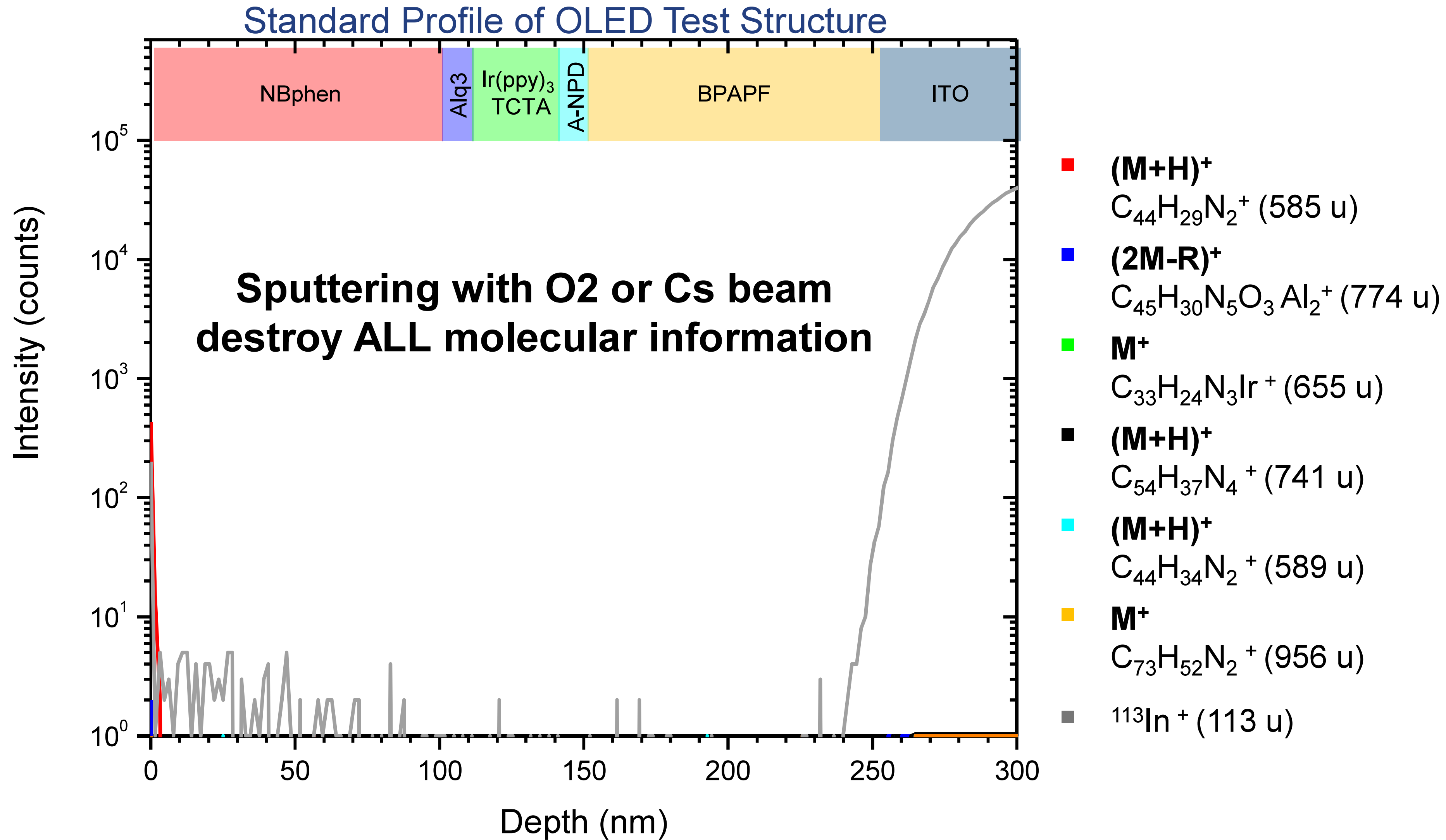
OLED Profiling with O2 beam sputtering



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OLED Profiling using Ar cluster

all layers well resolved, intact molecules detected with high yield for all layers

NBphen | Alq3 | Ir(ppy)$_3$ TCTA | A-NPD | BPAPF | ITO

Intensity (counts)

Depth (nm)

- (M+H)$^+$ $C_{44}H_{29}N_2^+$ (585 u)
- (2M-R)$^+$ $C_{45}H_{30}N_5O_3Al_2^+$ (774 u)
- M$^+$ $C_{33}H_{24}N_3Ir^+$ (655 u)
- (M+H)$^+$ $C_{54}H_{37}N_4^+$ (741 u)
- (M+H)$^+$ $C_{44}H_{34}N_2^+$ (589 u)
- M$^+$ $C_{73}H_{52}N_2^+$ (956 u)
- $^{113}In^+$ (113 u)

Drawback: Ar cluster will NOT sputter inorganic materials

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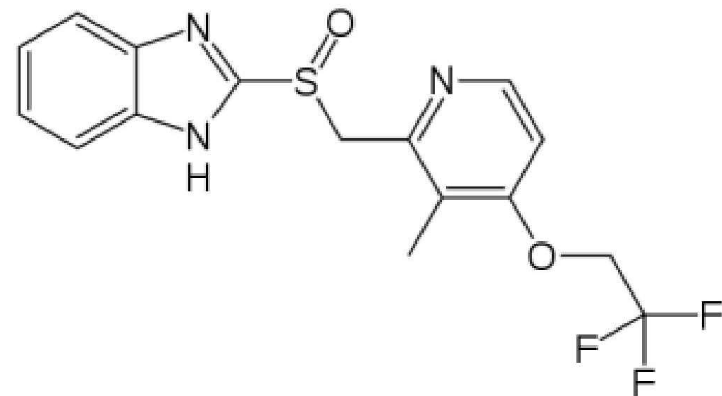
Chemical Imaging of Finished Drug

Product: Delayed release proton pump inhibitor

API:

Lansoprazole, $C_{16}H_{14}F_3N_3O_2S$, 369.363 amu



Inorganic excipients:

SiO_2, $MgCO_3$, Talc, TiO_2

Organic excipients:

Hydroxypropyl cellulose
Methacrylic acid co-polymer
Polyethylene glycol (PEG)
Sucrose

Objective: 2-dimensional imaging of API and excipients to determine location within product

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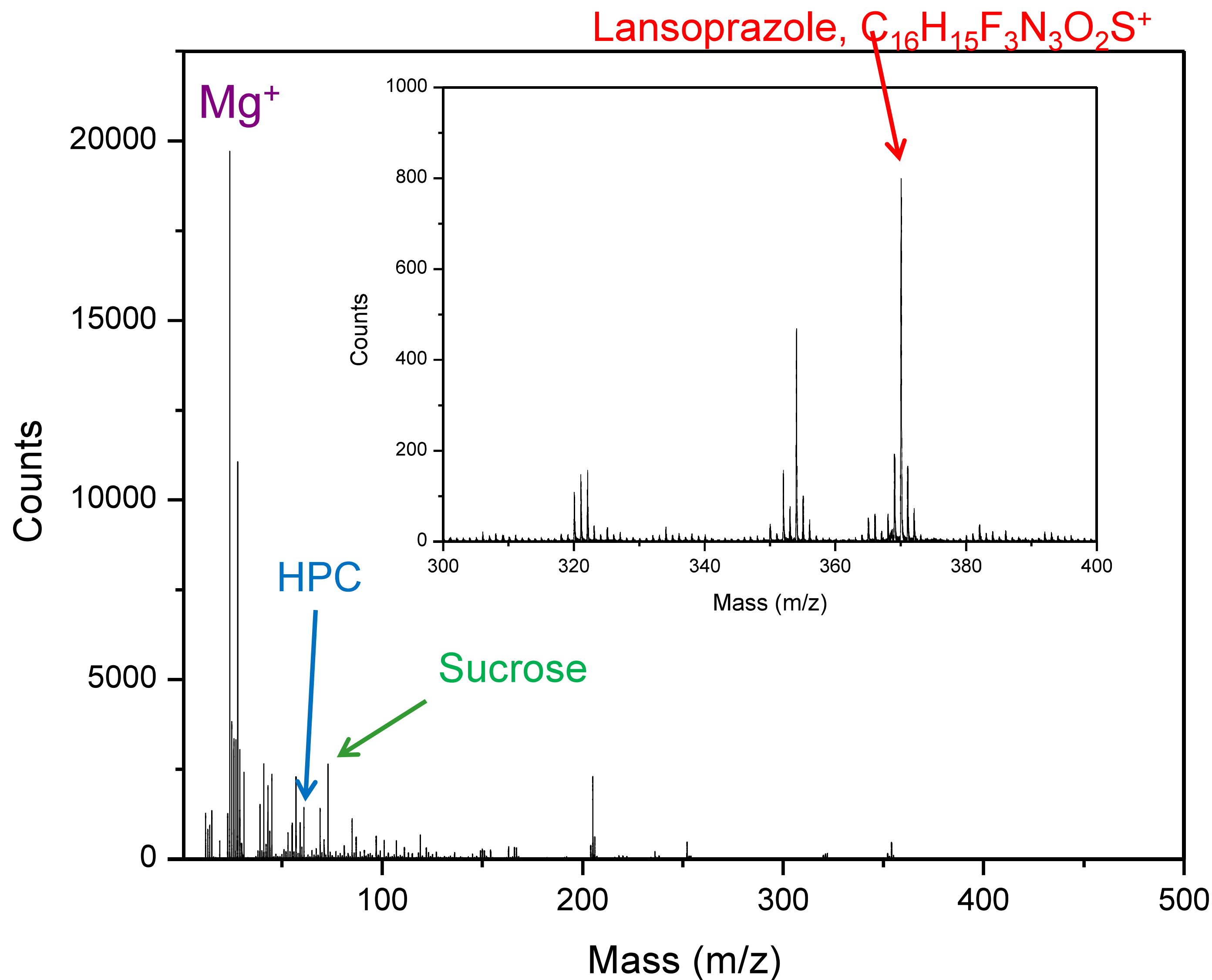
TOF Mass Spectrum (+ ions)

Identify unique ion(s) for each compound in sample in the mass spectrum.



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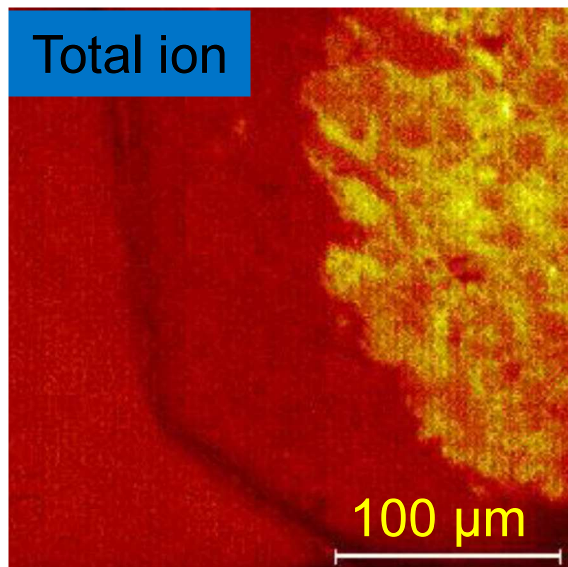
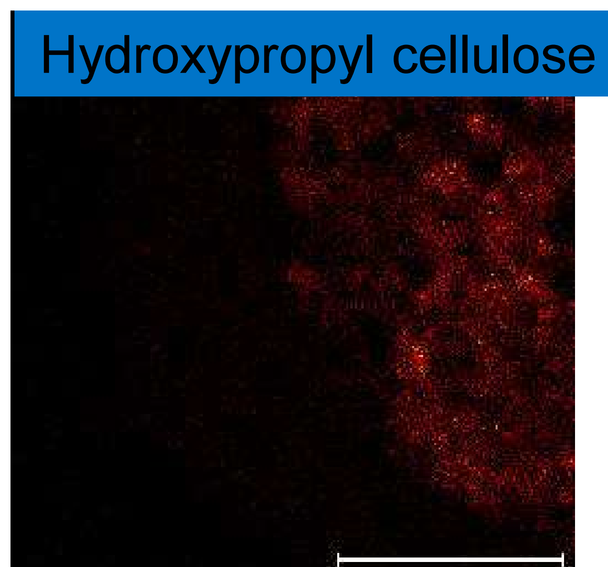
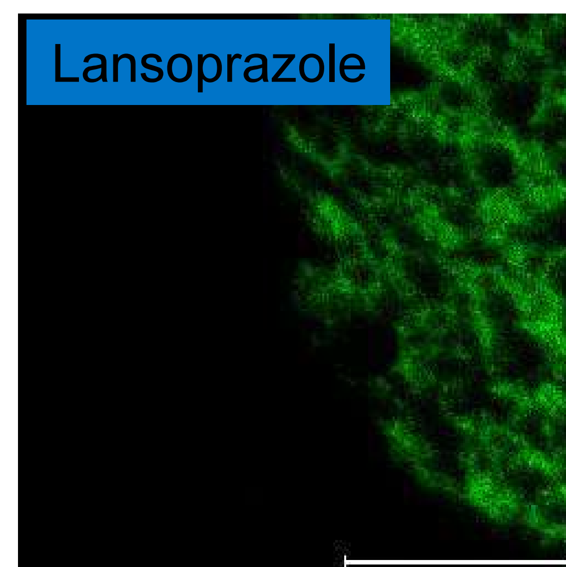
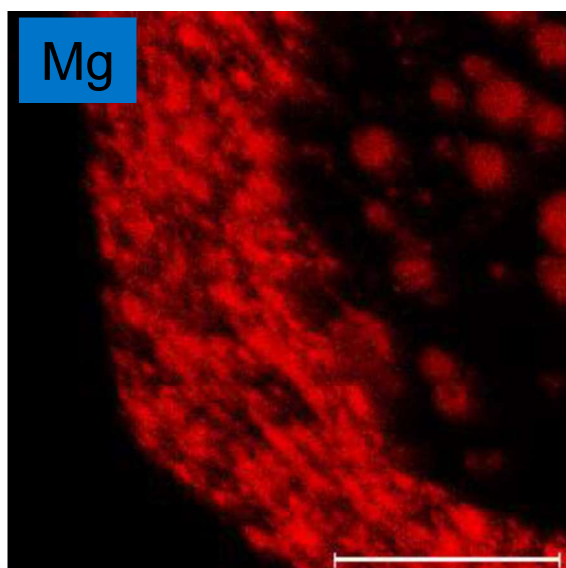
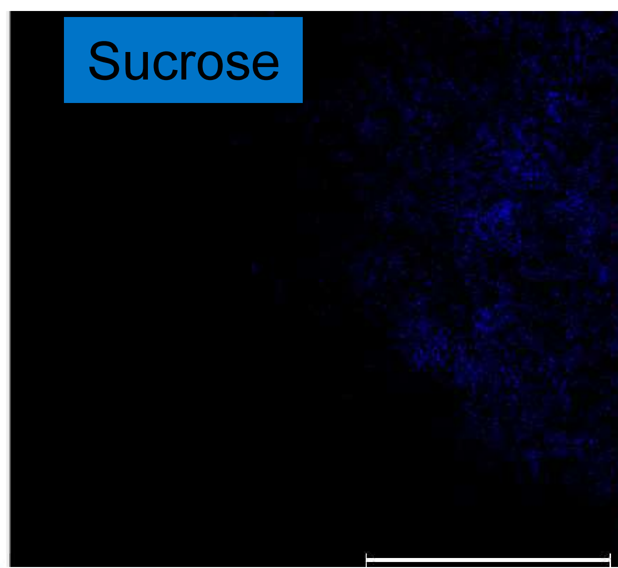
2-D TOF-SIMS Molecular Imaging

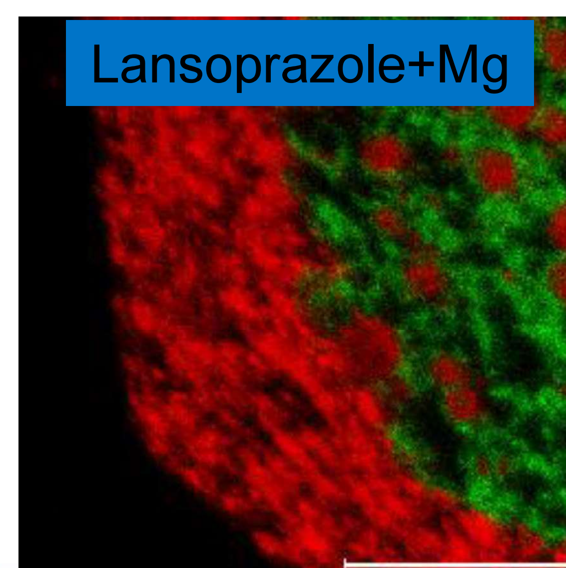












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2-D Imaging of Finished Drug

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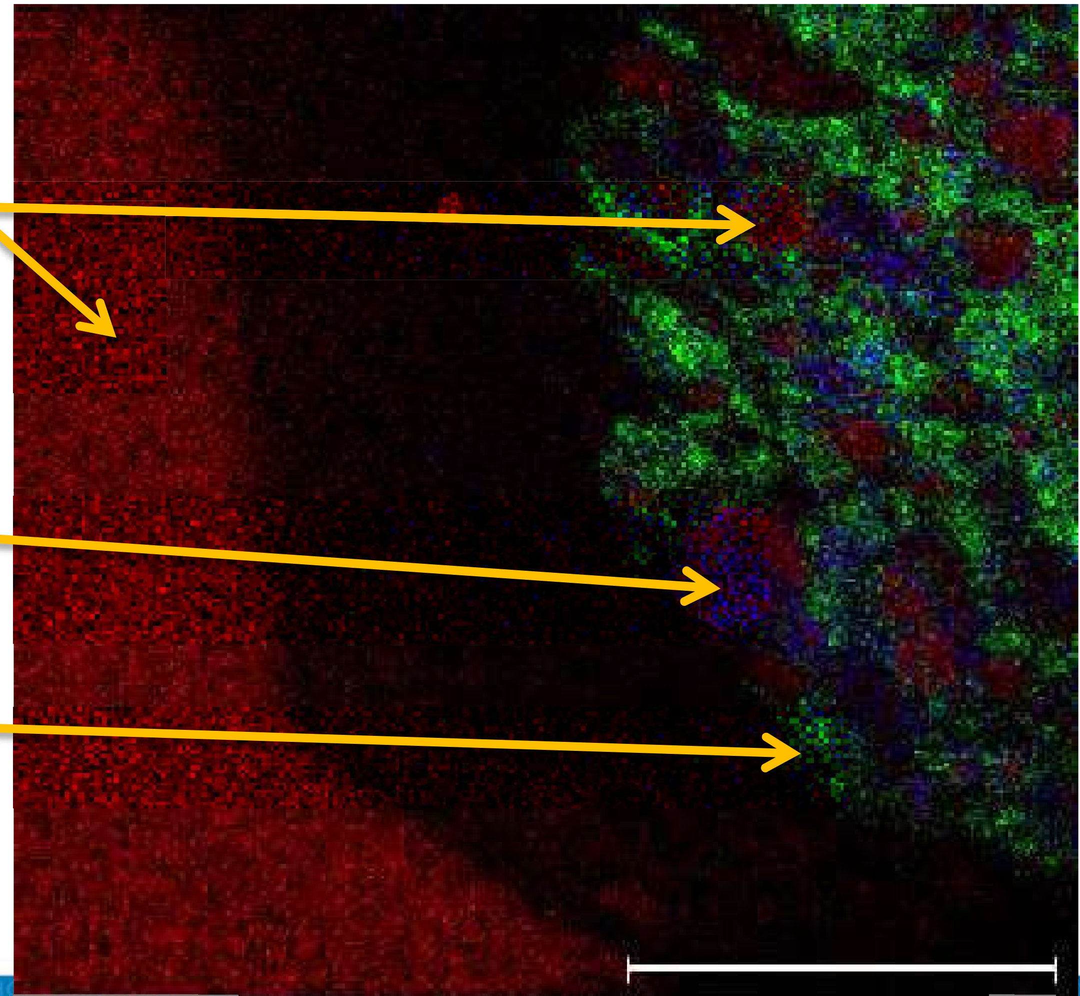
SEM-EDS used to determine location/distribution of inorganic constituents

TOF-SIMS is able to map inorganic and organic constituents

Cl (from epoxy and minor contaminant in $MgCO_3$)

Sucrose

Lansoprazole



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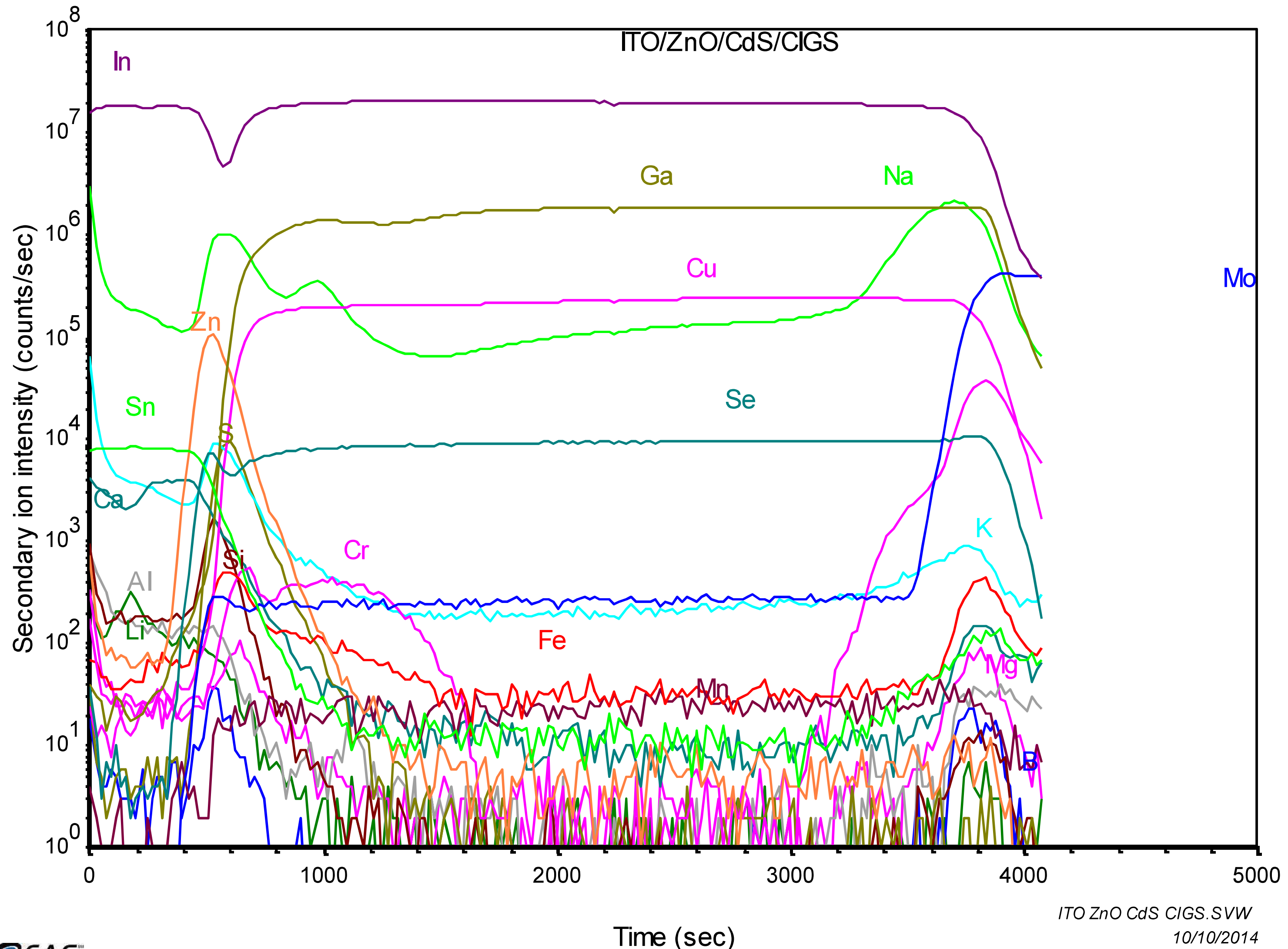
Depth Profiles of inorganic materials -O2/Cs beam

Survey Depth Profile –ITO/ZnO/CIGS using O2 beam



Detection sensitivities of inorganic profiling using TOF is 100-10,000 times poorer than using Dynamic SIMS

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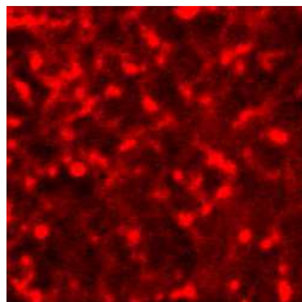
TOF- High Lateral Resolution Images

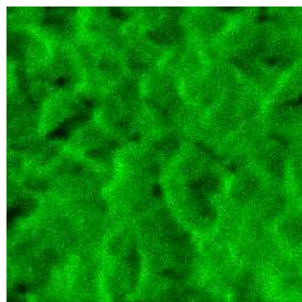
Na in CIGS

9.6 x 9.6 μm²

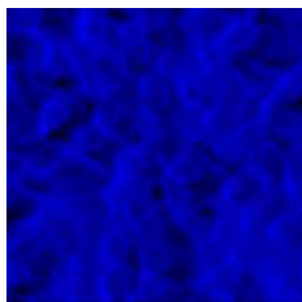
Na+

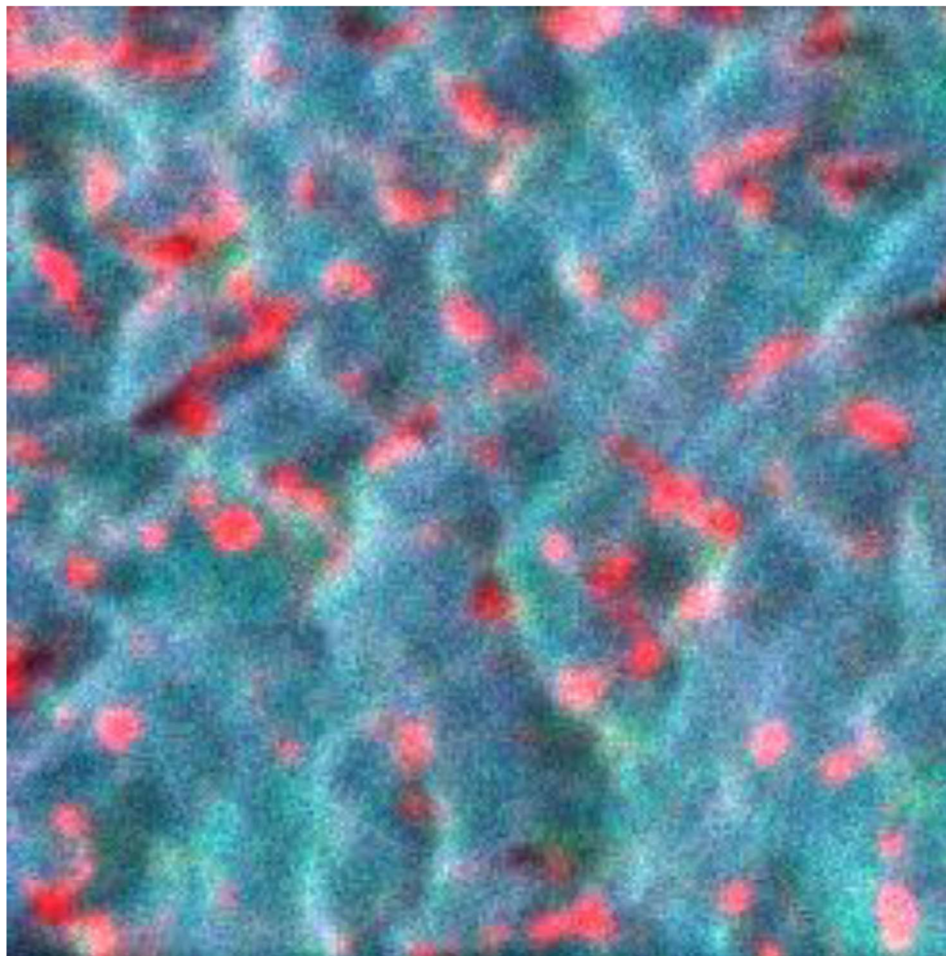


Ga+



In+





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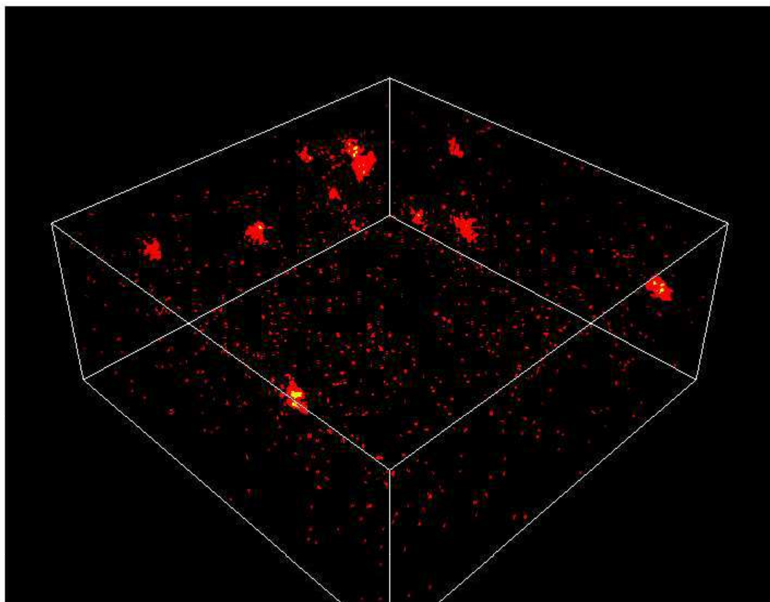
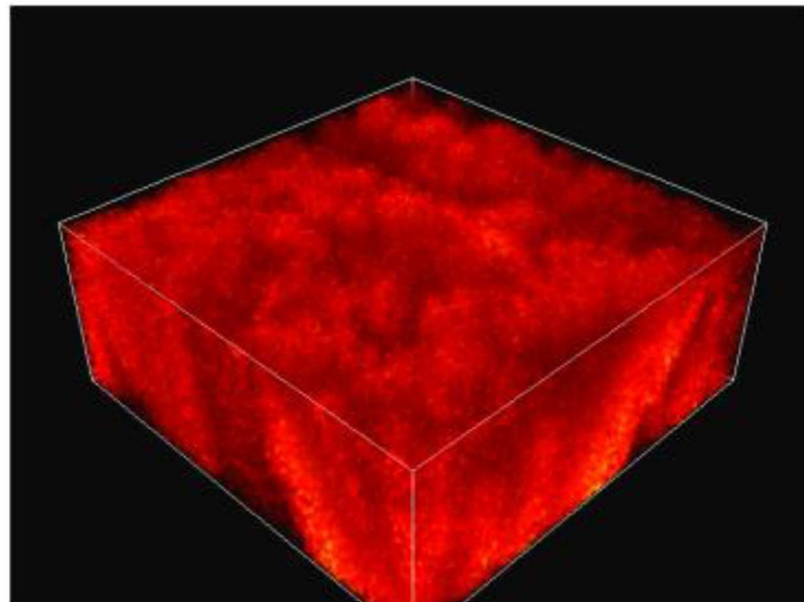
TOF 3-D Analysis

O2 beam sputtering of Al

75x75x3 um



Ti



Al

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Summary

- Strengths
  - elemental and molecular information on thin (submonolayer) organic films/contaminants
  - survey analysis
  - ppm detection limits
  - small spot size (0.1 µm) and mapping
  - analyzes insulators and conductors
  - Molecular Profiling and 3D images
- Limitations
  - organic information can be limited
  - vacuum compatibility required
  - Quantification very difficult
  - at times, too surface sensitive

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